

PATENT#10
D.Scott
10-2582

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: MAJIMA et al. Examiner: Le, Dung Anh

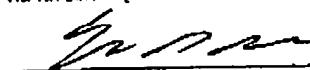
Serial No.: 09/890,550 Group No.: 2818

Filed: January 14, 2002

Title: POROUS SILICON CARBIDE SINTER AND SILICON CARBIDE-METAL COMPOSITE THAT ARE OPTIMAL FOR A WAFER GRINDER TABLE

RESPONSE TO RESTRICTION REQUIREMENTCERTIFICATE OF FACSIMILE TRANSMISSION

I hereby certify that this correspondence is being transmitted to the Commissioner for Patents, Washington, DC 20231, via facsimile (fax no. 703-872 9318) on October 11, 2002.

 Reg. No. 40,764
Mark D. PasslerVIA FACSIMILE (703 872 9318)

Tech Center 2800

Commissioner for Patents
Washington, D.C. 20231**FAX COPY RECEIVED**

OCT 11 2002

Sir:

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This response is in reply to a restriction requirement set forth in the Office Action dated September 13, 2002, in the above-identified application, with a one month shortened statutory period, making a response due on or before October 13, 2002. This response is timely filed.

REMARKS

In the above-identified Office Action, the Examiner has issued a restriction requirement and requires election of one of the following species under 35 U.S.C. § 121:

Group I: Claims 20-27, 29-40 and 43-46, drawn to a semiconductor device, classified in class 25; or

Group II: Claims 28 and 41-42, drawn to a process of making a semiconductor device, classified in class 438, and subclass 409.